

#5/PRE-AMEND
C. Que
7/26/02
[10191/1264A]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Kurt BURGER et al.
Serial No. : To Be Assigned
For : METHOD AND DEVICE FOR VACUUM-COATING
A SUBSTRATE
Examiner : To Be Assigned
Group Art Unit : To Be Assigned

Assistant Commissioner
for Patents
Washington, D.C. 20231

SUPPLEMENTAL PRELIMINARY AMENDMENT

SIR:

As a supplement to the Preliminary Amendment filed herewith, please further amend the above-identified application before examination, as set forth below.

IN THE CLAIMS:

In addition to the previously canceled original claims 1-35, please also cancel claims 36-77, without prejudice in the newly submitted English translation, and please add the following new claims:

78. (New) A plasma CVD device for vacuum coating a substrate, comprising:
- a vacuum recipient;
 - a bearing device for receiving the substrate to be coated;
 - an arrangement for producing a plasma in an interior of the vacuum recipient and including one of a microwave source, a sputter cathode, a system for producing a high-current arc, and a hollow cathode; and
 - a device, capable of being controlled separately from the arrangement for producing the plasma, for producing a substrate voltage that is applied to the substrate to be coated, wherein the device for producing the substrate voltage includes a direct voltage power supply unit that can be pulsed in bipolar fashion so that at least one of a length and a height of a positive pulse and a negative pulse of the substrate voltage